

Contents

Agradecimientos	vii
Abstract	ix
Resumen	xi
Resum	xiii
Table of contents	xv
List of figures	xvii
List of tables	xxi
1 Introduction	1
1.1 Integrated photonics platforms	2
1.2 Silicon Nitride Platforms: State of the art.	3
1.3 Integrated sensors	7
1.4 Objectives	8
1.5 Thesis outline	8
2 Silicon Nitride Photonic Integration Platform	11
2.1 Silicon nitride platform 300 nm film height.	11
2.2 Fabrication Process.	12
2.3 Si ₃ N ₄ waveguide simulations.	13
2.4 Measurement setup and test structures.	14
2.5 Propagation Loss.	15
2.6 Group Index and Dispersion.	17
2.7 Fabrication Process Steps Variations.	18
2.7.1 Propagation loss discussion.	19
2.7.2 Propagation constant and derivatives discussion	22
2.8 Conclusions	24

3	Integrated Optical Spectroscopic Sensor	27
3.1	IOSS device concept	27
3.2	Device operation description.	30
3.3	Design procedure	35
	3.3.1 Readout Scheme: Output Waveguides Distances	36
	3.3.2 Readout Scheme: Optical Frequencies	38
	3.3.3 Focusing and Periodicity: Arm spacing and FPR length	39
3.4	Reference Designs	40
	3.4.1 Visible Wavelength Range Device	41
	3.4.2 Near Infrared Device	44
3.5	Conclusions	46
4	IOSS proof-of-concept	49
4.1	Proof of concept	49
	4.1.1 Design and simulation	49
	4.1.2 Characterization	52
	4.1.3 Sensing measurements	55
4.2	Refined IOSS designs	57
4.3	Conclusions	61
5	Conclusions and future work	63
5.1	Conclusions	63
5.2	Future work	64
5.3	List of publications	64
	References	67